

## **Epitaxial growth and magnetic properties of FeSi<sub>2</sub> thin films grown on GaAs(100)**

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$\beta$ -FeSi<sub>2</sub> is a nonmagnetic semiconductor material with a band gap of 0.83~0.87 eV. The crystal structure of  $\beta$ -FeSi<sub>2</sub> is base-centered orthorhombic having 48 atoms per unit cell and lattice parameters  $a=9.863$  Å,  $b=7.884$  Å, and  $c=7.791$  Å [1-3]. We have made epitaxial FeSi<sub>2</sub> thin films on GaAs(100) substrate by using molecular beam epitaxy (MBE). The base pressure of the chamber was  $5.0 \times 10^{-9}$  Torr. The growth rate and substrate temperature were  $0.27$  Å/s and  $T_S=470$  °C, respectively. Figure 1 shows a streaky RHEED pattern and X-ray diffraction pattern of FeSi<sub>2</sub> thin film grown on GaAs(100) substrate, indicating the layer-by-layer growth and c-axis orientation of FeSi<sub>2</sub> thin films on GaAs(100). In this talk we will present the growth temperature dependent and thickness dependent properties of  $\beta$ -FeSi<sub>2</sub> thin films.

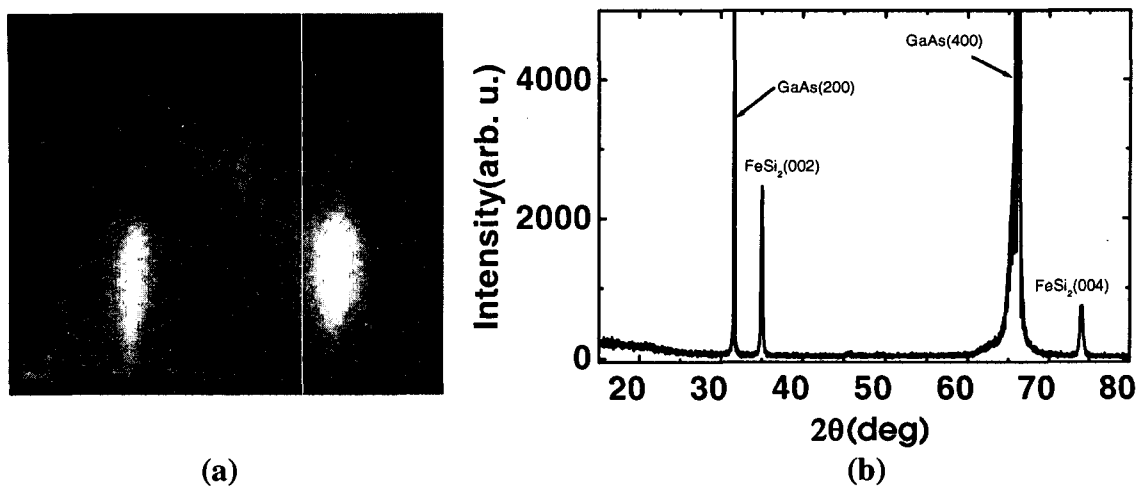


Figure 1. (a) RHEED pattern of FeSi<sub>2</sub> thin film on GaAs(100) at  $T_S=470$  °C. (b) X-ray diffraction of FeSi<sub>2</sub> thin film on GaAs(100).

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